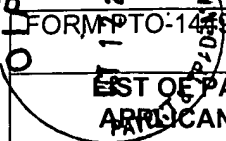
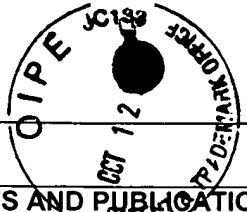


FORM PTO-1449

 	SERIAL NO. 09/876,451	CASE NO. 7103/238
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)	FILING DATE June 7, 2001	GROUP ART UNIT To Be Assigned
APPLICANT(S): Walters et al.		

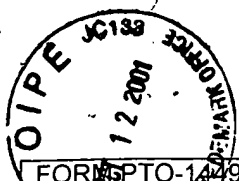
FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES
<i>hm</i>	A34	WO 99/22908	05/14/99	PCT	

EXAMINER INITIAL	OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
<i>hm</i>	A35	S. Inaba, T. Katsuyama, M. Tanaka, "Study of CMP Polishing pad Control Method," 1998 CMP-MIC Conference, February 19-20, 1998, 1998 IMIC - 300P/98/0444.
<i>hm</i>	A36	MegaSonics Cleaner Products, http://www.prosysmeg.com/html/body_prod_transducer.html .
<i>hm</i>	A37	ProSys Product Systems Inc., http://www.prosysmeg.com/body_index.html .
<i>hm</i>	A38	U.S. Patent Application Serial No. 09/475,518: "METHOD AND APPARATUS FOR CONDITIONING A POLISHING PAD"; Inventor: Finkelman; Filed: December 30, 1999; Attorney Docket No. 7103-117
<i>hm</i>	A39	U.S. Patent Application Serial No. 09/540,385: "METHOD AND APPARATUS FOR CHEMICALLY-MECHANICALLY POLISHING SEMICONDUCTOR WAFERS"; Inventors: Travis et al.; Filed March 31, 2000; Attorney Docket No. 7103-123
<i>hm</i>	A40	U.S. Patent Application Serial No. 09/540,602: "METHOD AND APPARATUS FOR CONDITIONING A POLISHING PAD"; Inventor: John M. Boyd; Filed March 31, 2000; Attorney Docket No. 7103-133
<i>hm</i>	A41	U.S. Patent Application Serial No. 09/540,810: "FIXED ABRASIVE LINEAR POLISHING BELT AND SYSTEM"; Inventors: Zhao et al.; Filed March 31, 2000; Attorney Docket No. 7103-135
<i>hm</i>	A42	U.S. Patent Application Serial No. 09/541,144: "METHOD AND APPARATUS FOR CHEMICAL MECHANICAL PLANARIZATION AND POLISHING OF SEMICONDUCTOR WAFERS USING A CONTINUOUS POLISHING MEMBER FEED"; Inventors: Mooring et al.; Filed March 31, 2000; Attorney Docket No. 7103-165
<i>hm</i>	A43	U.S. Patent Application Serial No. 09/607,743: "A CONDITIONING MECHANISM IN A CHEMICAL MECHANICAL POLISHING APPARATUS FOR SEMICONDUCTOR WAFERS"; Inventors: Vogtmann et al.; Filed June 30, 2000; Attorney Docket No. 7103-173
<i>hm</i>	A44	U.S. Patent Application Serial No. 09/607,895: "APPARATUS AND METHOD FOR CONDITIONING A FIXED ABRASIVE POLISHING PAD IN A CHEMICAL MECHANICAL PLANARIZATION PROCESS"; Inventors: Ravkin et al.; Filed June 30, 2000; Attorney Docket No. 7103-180
<i>hm</i>	A45	U.S. Pending Patent Application Serial No. 09/796,955, Entitled "METHOD AND APPARATUS FOR CONDITIONING A POLISHING PAD WITH SONIC ENERGY," Filed February 28, 2001; Attorney Docket No. 7103-189
<i>hm</i>	A46	U.S. Pending Patent Application Serial No. 09/754,702, Entitled "METHOD AND APPARATUS FOR CONDITIONING A POLISHING PAD WITH SONIC ENERGY," Filed January 4, 2001; Attorney Docket No. 7103-190

EXAMINER <i>hm</i>	DATE CONSIDERED 8/21/03
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LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)	SERIAL NO. 09/876,451	CASE NO. 7103/238
	FILING DATE June 7, 2001	GROUP ART UNIT To Be Assigned
APPLICANT(S): Walters et al.		

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
<i>sm</i>	A1	3,753,269	08/21/73	Budman	
<i>sm</i>	A2	4,318,250	03/09/82	Klievoneit et al.	
<i>sm</i>	A3	4,672,985	06/16/87	Mohr	
<i>sm</i>	A4	4,720,939	01/26/88	Simpson et al.	
<i>sm</i>	A5	4,934,102	06/19/90	Leach et al.	
<i>sm</i>	A6	5,081,051	01/14/92	Mattingly et al.	
<i>sm</i>	A7	5,335,453	08/09/94	Baldy et al.	
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<i>sm</i>	A10	5,536,202	7/16/96	Appel et al.	
<i>sm</i>	A11	5,547,417	08/20/96	Breivogel et al.	
<i>sm</i>	A12	5,558,568	09/24/96	Talieh et al.	
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<i>sm</i>	A14	5,593,344	01/14/97	Weldon et al.	
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<i>sm</i>	A16	5,622,526	04/22/97	Phillips	
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EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES NO
<i>sm</i>	A33	WO 98/45090	10/15/98	PCT	

EXAMINER: <i>Steve Wark</i>	DATE CONSIDERED 8/21/03
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